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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Takashi OHSAKO et al.

Attorney Docket No. 2003_1364A

Confirmation No. 8585

Serial No. 10/677,221

Group Art Unit 2895

Filed October 3, 2003

Examiner Joannie A. Garcia

METHOD OF MANUFACTURING
SEMICONDUCTOR ELEMENT**Mail Stop: Issue Fee****REQUEST FOR INITIALED COPY OF PTO-1449**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

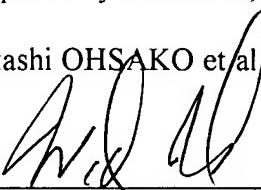
Sir:

The Examiner has provided an initialed copy of the form PTO-1449 submitted with the IDS filed May 10, 2005, indicating that all of the references *except* reference AJ (JP 08-250723) were considered. The Examiner crossed through reference AJ, and indicated in the margin that no copy of that reference was provided. However, a review of the application papers filed in connection with this application indicates that the USPTO apparently attached this reference to the back of reference AI (JP 07-183515) submitted with the same IDS. Thus, a copy of this reference, along with the required English language abstract, *was* properly submitted in a timely manner. Further, the Applicants assume that the Examiner has properly considered all of the information contained in reference AJ since this was attached to the back of reference AI. Consequently, the Examiner is requested to provide another initialed copy of the form PTO-1449 submitted with the IDS of May 10, 2005, properly indicating that AJ has been considered.

Respectfully submitted,

Takashi OHSAKO et al

By


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